



Electronic Filing System (EFS) Data
Electronic Patent Application Submission
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EFS ID: 52995

Application ID: 10663603



Title of Invention:

METHODS AND SYSTEMS FOR
INSPECTION OF AN ENTIRE
WAFER SURFACE USING MULTIPLE
DETECTION CHANNELS

First Named Inventor: Lionel Kuhlmann

Domestic/Foreign Application: Domestic Application

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Statement

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Confirmation number: 3534

Attorney Docket Number: 5589-06100


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**TRANSMITTAL**

Electronic Version v1.1
Stylesheet Version v1.1.0

Title of Invention	METHODS AND SYSTEMS FOR INSPECTION OF AN ENTIRE WAFER SURFACE USING MULTIPLE DETECTION CHANNELS									
<p>Application Number: 10/663603 </p> <p>Date: 2003-09-16</p> <p>First Named Applicant: Lionel Kuhlmann</p> <p>Confirmation Number: 3534</p> <p>Attorney Docket Number: 5589-06100</p>										
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<table border="1"><thead><tr><th>Submitted by:</th><th>Elec. Sign.</th><th>Sign. Capacity</th></tr></thead><tbody><tr><td>Kevin L. Daffer Registered Number: 34146</td><td>Kevin L. Daffer</td><td>Attorney</td></tr></tbody></table>			Submitted by:	Elec. Sign.	Sign. Capacity	Kevin L. Daffer Registered Number: 34146	Kevin L. Daffer	Attorney		
Submitted by:	Elec. Sign.	Sign. Capacity								
Kevin L. Daffer Registered Number: 34146	Kevin L. Daffer	Attorney								
<table><tr><td>Documents being submitted</td><td>Files</td></tr><tr><td>us-ids</td><td>558906100IDS-usidst.xml</td></tr><tr><td></td><td>us-ids.dtd</td></tr><tr><td></td><td>us-ids.xsl</td></tr></table>			Documents being submitted	Files	us-ids	558906100IDS-usidst.xml		us-ids.dtd		us-ids.xsl
Documents being submitted	Files									
us-ids	558906100IDS-usidst.xml									
	us-ids.dtd									
	us-ids.xsl									
Comments										



ELECTRONIC INFORMATION DISCLOSURE STATEMENT

Electronic Version v18

Stylesheet Version v18.0

Title of
Invention

METHODS AND SYSTEMS FOR INSPECTION OF AN
ENTIRE WAFER SURFACE USING MULTIPLE
DETECTION CHANNELS

Application Number: 10/663603



Confirmation Number: 3534

First Named Applicant: Lionel Kuhlmann

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or 6538730 or 6509965 or 6507394 or 6356346
or 6020957 or 5355212 or 6407809 or 6515742
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or 5623340 or 5604585 or 5585916 or 4632546
or 20030030050 or 20030030795 or
20020149765 or 20020145732 or
20010028454).pn.

US Patent Documents

Note: Applicant is not required to submit a paper copy of cited US Patent Documents

init	Cite.No.	Patent No.	Date	Patentee	Kind	Class	Subclass
	1	6271916	2001-08-07	Marxer et al.			
	2	6204917	2001-03-20	Smedt			
	3	6559938	2003-05-06	Smedt			
	4	6201601	2003-03-13	Vaez-Iravani et al.			
	5	6538730	2003-03-25	Vaez-Iravani et al.			
	6	6509965	2003-01-21	Fossey et al.			
	7	6507394	2003-01-14	Cheng et al.			
	8	6356346	2002-03-12	Hagen et al.			
	9	6020957	2000-02-01	Rosengaus et al.			
	10	5355212	1994-10-11	Wells et al.			
	11	6407809	2002-06-18	Finarov et al.			
	12	6515742	2003-02-04	Ruprecht			
	13	6496256	2002-12-17	Eytan et al.			

	14	6034776	2000-03-07	Germer et al.
	15	5999266	1999-12-07	Takahashi et al.
	16	5801824	1998-09-01	Henley
	17	5623340	1997-04-22	Yamamoto et al.
	18	5604585	1997-02-18	Johnson et al.
	19	5585916	1996-12-17	Miura et al.
	20	4632546	1986-12-30	Sick et al.

US Published Applications

Note: Applicant is not required to submit a paper copy of cited US Published Applications

init	Cite.No.	Pub. No.	Date	Applicant	Kind	Class	Subclass
	1	20030030050	2003-02-13	Choi			
	2	20030030795	2003-02-13	Swan et al.			
	3	20020149765	2003-10-17	Fujii et al.			
	4	20020145732	2003-10-10	Vaez-Iravani et al.			
	5	20010028454	2001-10-11	Savareigo			

Signature

Examiner Name	Date